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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/511,389	03/03/2005	Michael Geisler	19232.0017U1	2075

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EXAMINER

ZERVIGON, RUDY

ART UNIT	PAPER NUMBER
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1763

DATE MAILED: 04/17/2006

Please find below and/or attached an Office communication concerning this application or proceeding.

Office Action Summary

Application No.

10/511,389

Applicant(s)

GEISLER ET AL.

Examiner

Rudy Zervigon

Art Unit

1763

-- The MAILING DATE of this communication appears on the cover sheet with the correspondence address --

Period for Reply

A SHORTENED STATUTORY PERIOD FOR REPLY IS SET TO EXPIRE 3 MONTH(S) OR THIRTY (30) DAYS, WHICHEVER IS LONGER, FROM THE MAILING DATE OF THIS COMMUNICATION.

- Extensions of time may be available under the provisions of 37 CFR 1.136(a). In no event, however, may a reply be timely filed after SIX (6) MONTHS from the mailing date of this communication.
- If NO period for reply is specified above, the maximum statutory period will apply and will expire SIX (6) MONTHS from the mailing date of this communication.
- Failure to reply within the set or extended period for reply will, by statute, cause the application to become ABANDONED (35 U.S.C. § 133). Any reply received by the Office later than three months after the mailing date of this communication, even if timely filed, may reduce any earned patent term adjustment. See 37 CFR 1.704(b).

Status

- 1) ☒ Responsive to communication(s) filed on 11 August 2005.
- 2a) ☐ This action is **FINAL**. 2b) ☒ This action is non-final.
- 3) ☐ Since this application is in condition for allowance except for formal matters, prosecution as to the merits is closed in accordance with the practice under *Ex parte Quayle*, 1935 C.D. 11, 453 O.G. 213.

Disposition of Claims

- 4) ☒ Claim(s) 1-11 is/are pending in the application.
- 4a) Of the above claim(s) _____ is/are withdrawn from consideration.
- 5) ☐ Claim(s) _____ is/are allowed.
- 6) ☒ Claim(s) 1-11 is/are rejected.
- 7) ☐ Claim(s) _____ is/are objected to.
- 8) ☐ Claim(s) _____ are subject to restriction and/or election requirement.

Application Papers

- 9) ☐ The specification is objected to by the Examiner.
- 10) ☐ The drawing(s) filed on _____ is/are: a) ☐ accepted or b) ☐ objected to by the Examiner.
Applicant may not request that any objection to the drawing(s) be held in abeyance. See 37 CFR 1.85(a).
Replacement drawing sheet(s) including the correction is required if the drawing(s) is objected to. See 37 CFR 1.121(d).
- 11) ☐ The oath or declaration is objected to by the Examiner. Note the attached Office Action or form PTO-152.

Priority under 35 U.S.C. § 119

- 12) ☒ Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).
- a) ☒ All b) ☐ Some * c) ☐ None of:
- ☐ Certified copies of the priority documents have been received.
 - ☐ Certified copies of the priority documents have been received in Application No. _____.
 - ☒ Copies of the certified copies of the priority documents have been received in this National Stage application from the International Bureau (PCT Rule 17.2(a)).

* See the attached detailed Office action for a list of the certified copies not received.

Attachment(s)

- ☒ Notice of References Cited (PTO-892)
- ☐ Notice of Draftsperson's Patent Drawing Review (PTO-948)
- ☒ Information Disclosure Statement(s) (PTO-1449 or PTO/SB/08)
Paper No(s)/Mail Date All.
- ☐ Interview Summary (PTO-413)
Paper No(s)/Mail Date. _____.
- ☐ Notice of Informal Patent Application (PTO-152)
- ☐ Other: _____.

DETAILED ACTION

Claim Rejections - 35 USC § 112

1. The following is a quotation of the first paragraph of 35 U.S.C. 112:

The specification shall contain a written description of the invention, and of the manner and process of making and using it, in such full, clear, concise, and exact terms as to enable any person skilled in the art to which it pertains, or with which it is most nearly connected, to make and use the same and shall set forth the best mode contemplated by the inventor of carrying out his invention.

2. Claim 9 is rejected under 35 U.S.C. 112, first paragraph, as failing to comply with the enablement requirement. The claims contains subject matter which was not described in the specification in such a way as to enable one skilled in the art to which it pertains, or with which it is most nearly connected, to make and/or use the invention. Claim 9 requires cathode rotation, however, the specification does not sufficiently describe supporting structure therefore.

Claim Rejections - 35 USC § 103

3. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negated by the manner in which the invention was made.

4. Claims 1-3, 8, 10, and 11 are rejected under 35 U.S.C. 103(a) as being unpatentable over Szczyrkowski, Joachim et al. (US 20020157945 A1) in view of Mikata, Yuichi (US 20010012697 A1). Szczyrkowski teaches a coating installation (Figure 1; Section [0013]-[0015]) with a vacuum chamber (5; Figure 1; Section [0013]-[0015]) exhibiting an suction port (17; Figure 1) and a gas feed (9,10; Figure 1), in which a sputtering cathode (7; Figure 1) and a substrate holder (substrate :mounted"; not shown; [0013]) are arranged and for which the vacuum chamber (5; Figure 1; Section [0013]-[0015]) is divided into a cathode chamber (upper

Art Unit: 1763

5; Figure 1) and a substrate chamber (lower 5; Figure 1) by an screen (13'; Figure 1) arranged between the sputtering cathode (7; Figure 1) and the substrate holder (substrate :mounted"; not shown; [0013]) – claim 1

Szczyrbowski further teaches:

- i. Coating installation (Figure 1; Section [0013]-[0015]) in accordance with claim 1, characterized in that the sputtering cathode (7; Figure 1) is a double magnetron cathode, as claimed by claim 8
- ii. Coating installation (Figure 1; Section [0013]-[0015]) in accordance with claim 1, characterized in that a metering device (18; Figure 1) for reactive gas is arranged in the cathode chamber (upper 5; Figure 1) and that the regulated output (19; Figure 1) of the sputtering cathode (7; Figure 1) exhibited in the coating installation (Figure 1; Section [0013]-[0015]) is directly dependent on the concentration of the reactive gas in the cathode chamber (upper 5; Figure 1), as claimed by claim 10

Szczyrbowski does not teach:

- i. the cathode chamber (upper 5; Figure 1) as well as the substrate chamber (lower 5; Figure 1) each respectively exhibit a direct suction port (17; Figure 1) and their own gas feed (9,10; Figure 1), and that the gas feed (9,10; Figure 1) into the cathode chamber (upper 5; Figure 1) is connected to a process gas source and that the gas feed (9,10; Figure 1) for the substrate chamber (lower 5; Figure 1) is connected to a reactive gas source – claim 1
- ii. Coating installation (Figure 1; Section [0013]-[0015]) in accordance with claim 1, characterized in that the cathode chamber (upper 5; Figure 1) and the substrate chamber

Art Unit: 1763

(lower 5; Figure 1) are each respectively connected to their own vacuum pump stand (11, 17), as claimed by claim 2

- iii. Coating installation (Figure 1; Section [0013]-[0015]) in accordance with claim 1, characterized in that in the cathode chamber (upper 5; Figure 1) as well as in the substrate chamber (lower 5; Figure 1), the gas feed (9,10; Figure 1) and the suction port (17; Figure 1) are arranged on opposite sides, as claimed by claim 3
- iv. Coating installation (Figure 1; Section [0013]-[0015]) in accordance with claim 1, characterized in that the ratio of the focal aperture length of the screen (13'; Figure 1), measured in the transport direction of the substrate (8; Figure 1), to the width of the sputtering cathode (7; Figure 1), measured in the transport direction of the substrate (8; Figure 1), amounts to less than 0.75, preferably to between 0.5 and 0.3, as claimed by claim 11

Mikata teaches a deposition chamber (Figure 3) including a shutter (410; Figure 3) dividing the chamber in two. Each chamber is shown with its individual process gas supply (11,12) and exhaust ports (421, 419).

It would have been obvious to one of ordinary skill in the art at the time the invention was made for Szczyrkowski to add plural gas source ports and vacuum ports as taught by Mikata, and for Szczyrkowski to optimize the relative dimension of Szczyrkowski's apparatus.

Motivation for Szczyrkowski to add plural gas source ports and vacuum ports as taught by Mikata, and for Szczyrkowski to optimize the relative dimension of Szczyrkowski's apparatus is for promoting uniformity in process gas distribution to reduce nonuniform depositions as taught by Mikata ([0005]). Further, it is well established that the duplication of parts is obvious (In re

Art Unit: 1763

Harza , 274 F.2d 669, 124 USPQ 378 (CCPA 1960) MPEP 2144.04). Further, it is well established that changes in apparatus dimensions are within the level of ordinary skill in the art.(Gardner v. TEC Systems, Inc. , 725 F.2d 1338, 220 USPQ 777 (Fed. Cir. 1984), cert. denied , 469 U.S. 830, 225 USPQ 232 (1984); In re Rose , 220 F.2d 459, 105 USPQ 237 (CCPA 1955); In re Rinehart, 531 F.2d 1048, 189 USPQ 143 (CCPA 1976); See MPEP 2144.04)

5. Claims 4-7 are rejected under 35 U.S.C. 103(a) as being unpatentable over Szczyrkowski, Joachim et al. (US 20020157945 A1) and Mikata, Yuichi (US 20010012697 A1) in view of Szczyrkowski; Joachim et al. (US 5082546 A). Szczyrkowski and Mikata are discussed above. Szczyrkowski and Mikata do not teach:

- i. Coating installation (Figure 1; Section [0013]-[0015]) according to claim 1, characterized in that an anode is arranged in the vacuum chamber (5; Figure 1; Section [0013]-[0015]) between the sputtering cathode (7; Figure 1) and the substrate (8; Figure 1), as claimed by claim 4
- ii. Coating installation (Figure 1; Section [0013]-[0015]) in accordance with claim 1, characterized in that the anode in the substrate chamber (lower 5; Figure 1) is arranged to be covered by the screen (13'; Figure 1) between the screen (13'; Figure 1) and the substrate holder (substrate :mounted"; not shown; [0013]), as claimed by claim 5
- iii. Coating installation (Figure 1; Section [0013]-[0015]) in accordance with claim 1, characterized in that the anode is formed by two unheated tubes, as claimed by claim 6
- iv. Coating installation (Figure 1; Section [0013]-[0015]) in accordance with claim 1, characterized in that the anode simultaneously forms the screen (13'; Figure 1), as claimed by claim 7

Art Unit: 1763

Szczyrbowski; Joachim et al. (US 5082546 A) teaches a sputtering apparatus (Sole Figure; column 1; lines 14-40) including a tubular anode (6; Figure 1) arranged in the vacuum chamber between the cylindrical (tubular) sputtering cathode (3,3a-c; Sole Figure) and the substrate (1 Sole Figure). Lehan further teaches rotating cylindrical magnetron.

It would have been obvious to one of ordinary skill in the art at the time the invention was made for Szczyrbowski; Joachim et al. (US 20020157945 A1) and Mikata to add Szczyrbowski; Joachim et al. (US 5082546 A) anode.

Motivation for Szczyrbowski; Joachim et al. (US 20020157945 A1) and Mikata to add Szczyrbowski; Joachim et al. (US 5082546 A) anode is for arc-free and cleaning-free processing as taught by Szczyrbowski; Joachim et al. (US 5082546 A; column 1; lines 29-31).

6. Claim 9 is rejected under 35 U.S.C. 103(a) as being unpatentable over Szczyrbowski; Joachim et al. (US 20020157945 A1) and Mikata, Yuichi (US 20010012697 A1) in view of Lehan; John et al. (US 5814195 A). Szczyrbowski and Mikata are discussed above. Szczyrbowski and Mikata do not teach the coating installation (Figure 1; Section [0013]-[0015]) in accordance with claim 1, characterized in that the sputtering cathode (7; Figure 1) is a rotating cathode, as claimed by claim 9.

Lehan teaches a rotatable cylindrical magnetron (Figure 4) used in sputtering depositions.

It would have been obvious to one of ordinary skill in the art at the time the invention was made for Szczyrbowski; Joachim et al. (US 20020157945 A1) and Mikata to replace Szczyrbowski's magnetron with Lehan's rotatable cylindrical magnetron (Figure 4).

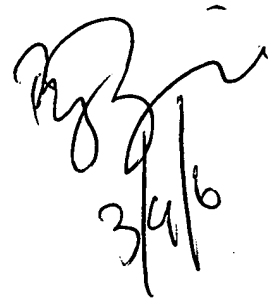
Motivation for Szczyrbowski; Joachim et al. (US 20020157945 A1) and Mikata to replace Szczyrbowski's magnetron with Lehan's rotatable cylindrical magnetron (Figure 4) is for

Art Unit: 1763

removing an anode as a contamination source during processing as taught by Lehan (column 1; lines 25-40).

Conclusion

7. Any inquiry concerning this communication or earlier communications from the examiner should be directed to Examiner Rudy Zervigon whose telephone number is (571) 272-1442. The examiner can normally be reached on a Monday through Thursday schedule from 8am through 7pm. The official fax phone number for the 1763 art unit is (571) 273-8300. Any Inquiry of a general nature or relating to the status of this application or proceeding should be directed to the Chemical and Materials Engineering art unit receptionist at (571) 272-1700. If the examiner can not be reached please contact the examiner's supervisor, Parviz Hassanzadeh, at (571) 272-1435.



3/4/6